

IN THE CLAIMS

Please amend the claims as follows:

Claim 1 (Currently Amended): A micro thermoelectric gas sensor comprising:
a membrane for heat shielding formed on a substrate[.,.];
a catalyst material that induces a catalytic reaction in contact with a gas to be
detected[.,.];
a thermoelectric conversion material film that converts a local temperature difference
produced by heat generation caused by the reaction into a voltage signal[, and.];
a microheater for temperature control for facilitating stable gas detection of the gas
sensor formed, which are on the membrane[.,.]; and
a high-temperature section and a low-temperature section of [[a]] the thermoelectric
thin film formed on the same membrane.

Claim 2 (Original): The thermoelectric gas sensor according to claim 1, wherein the
thermoelectric conversion material film is a segment of a thermocouple having a high-
temperature section and a low-temperature section.

Claim 3 (Original): The thermoelectric gas sensor according to claim 1, wherein the
thermoelectric conversion material film is a thermocouple having a high-temperature section
and a low-temperature section, a plurality of the thermocouples are provided, and the
plurality of thermocouples are connected in serial.

Claim 4 (Original): The thermoelectric gas sensor according to any one of claims 1
through 3, wherein a membrane with a thickness of 1 μm or less is obtained by wet etching a
rear surface of the substrate.

Claim 5 (Original): The thermoelectric gas sensor according to claim 4, wherein a plurality of membranes are provided on the substrate.

Claim 6 (Currently Amended): The thermoelectric gas sensor according to any one of claims 1 through [[5]] 3, wherein an insulating film is formed in a state of contact with the membrane on the membrane, a bonding film is formed on the insulating film in a state of contact with the insulating film and a heater for serving to bond the insulating film and the heater, and a catalytic material layer is formed in thermal contact with said heater being electrically insulated by the insulating film.

Claim 7 (Original): The thermoelectric gas sensor according to claim 1, wherein after a thermoelectric conversion material film pattern has been produced, the pattern is heat treated at a high temperature to improve crystallinity thereof.

Claim 8 (Currently Amended): The thermoelectric gas sensor according to any one of claims 1 through [[7]] 3, wherein a SiGe thin film is formed as the thermoelectric conversion material film.

Claims 9 – 24 (Canceled).

Claim 25 (New): The thermoelectric gas sensor according to claim 1, wherein the thermoelectric conversion material film extends in a linear section from a region of the catalyst material to a region of the microheater.

Claim 26. (New): The thermoelectric gas sensor according to claim 25, wherein the thermoelectric conversion material film measures a voltage due to a temperature difference across the linear section.

Claim 27 (New): The thermoelectric gas sensor according to claim 1, wherein a part of the catalyst material is disposed at a first periphery of said membrane and a part of the microheater is disposed at a second periphery of said membrane opposite the first periphery.

Claim 28. (New): The thermoelectric gas sensor according to claim 27, wherein the thermoelectric conversion material film extends in a linear section from the first periphery to the second periphery.

Claim 29. (New): The thermoelectric gas sensor according to claim 26, wherein the thermoelectric conversion material film measures a voltage due to a temperature difference across the linear section.